



Docket No.: A-68359-1/RMA (469113-41)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

First Named Inventor:	<b>MALONEY, et al.</b>	Examiner: ELY, TIMOTHY V
Appln. No.:	<b>10/027,935</b>	Group Art Unit: 3724
Filing Date:	<b>December 21, 2001</b>	Confirmation No. 2631
Title:	<b>Apparatus and Method for Chemical-Mechanical Polishing (CMP) Head Having Direct Pneumatic Wafer Polishing Pressure</b>	Certificate of Mailing I hereby certify that this correspondence is being deposited in the United States Mail, postage prepaid in an envelope addressed to Commissioner of Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on July 20, 2004. By: <u>Leslie Hoffmann</u> Leslie Hoffmann

**PETITION FOR EXTENSION OF PERIOD FOR RESPONSE**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Pursuant to 37 C.F.R. § 1.136(a), Applicant hereby petitions for an extension of two (2) months (from May 20, 2004 to July 20, 2004) within which to respond to the Office Action dated April 20, 2004. The extension fee of \$420.00 is included in the enclosed check. Please charge any additional fees or credit any overpayment to our Deposit Account No. 50-2319 (Order No. A-68359-1/RMA (469113-41)).

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Respectfully submitted,

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